

AMENDMENTS TO THE SPECIFICATION:

Replace the paragraph beginning on page 2, paragraph 7 with the following:

[0001] ~~Figure 3 shows~~ Figures 3 and 4 show an exemplary use of an undercut post complementary metal oxide semiconductor (CMOS) processing.

Replace the paragraph beginning on page 2, paragraph 8 with the following:

[0002] ~~Figures 4a-4c~~ Figures 5a-5c illustrate exemplary uses of MEMS actuators.

Replace the paragraph beginning on page 4, paragraph 15 with the following:

[0003] ~~Figure 3 shows~~ Figures 3 and 4 show an exemplary use of CMOS processing, or more particularly, an undercut post CMOS processing, to achieve a suspended beam of conductive material (i.e., suspended relative to an anchor post), that can serve to form any one or more of the dynamically movable conductors 105a-105c.

Replace the paragraph beginning on page 4, paragraph 16 with the following:

[0004] ~~Figures 4a-4c~~ Figures 5a-5c illustrate the use of MEMS actuators to achieve lift, lateral movement and rotation, respectively, of a conductor for altering characteristics of a signal path in accordance with exemplary embodiments. Of course, any type of motion that can be used to alter characteristics of the signal path can be incorporated into a structure designed in accordance with exemplary embodiments.